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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Hiroshi CHIBA

Application No.: 10/829,159

Filed: April 22, 2004

Docket No.: 104685.05

For: METHOD FOR ADJUSTING PROJECTION OPTICAL APPARATUS

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the reference(s) listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- ☒ 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- ☒ 2. An English-language translation of the attached reference is submitted herewith.

Respectfully submitted,

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MAC/ccs

Date: May 26, 2004

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Form PTO-1449 (REV. 8-83)		U.S. Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 104685.05		APPLICATION NO. 10/829,159	
				APPLICANT(S) Hiroshi CHIBA			
				FILING DATE April 22, 2004		GROUP	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)							
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)							
		"Nanometer Aspherics - How and for what Purpose are they Fabricated?", C. Hofmann et al., Optical Assemblies, Feinwerktechnik & Messtechnik 99 (1991), 10, pages 437-440, © Carl Hanser Verlag, Munich 1991.					
EXAMINER					DATE CONSIDERED		
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							